

Invention: WAFER PROBE STATION FOR LOW-CURRENT MEASUREMENTS  
 Filed: Herewith Attorney: Jacob E. Vilhauer, Jr., Reg. # 24,885  
 Inventors: Randy J. Schwindt et al. Telephone: (503) 227-5631

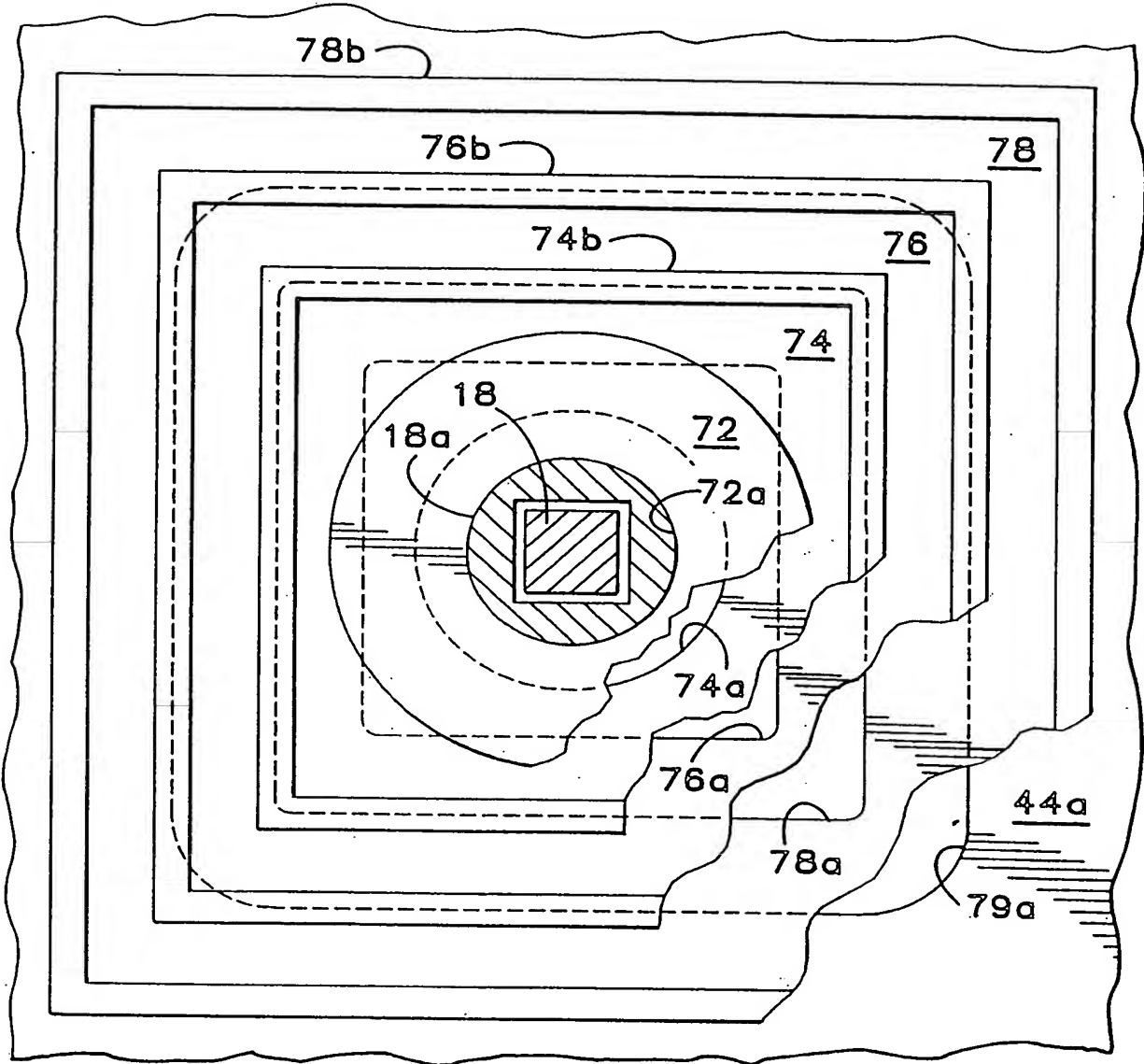
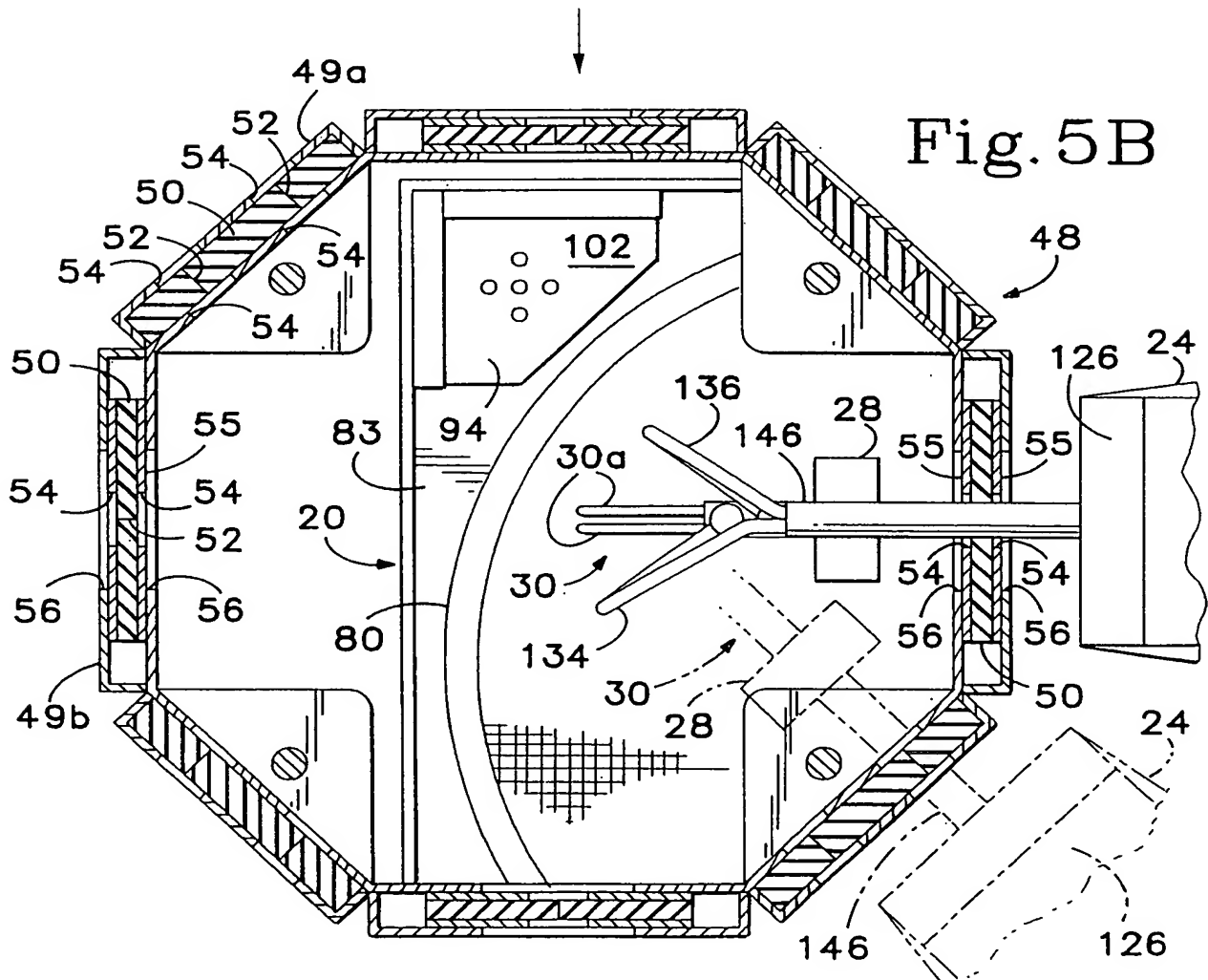
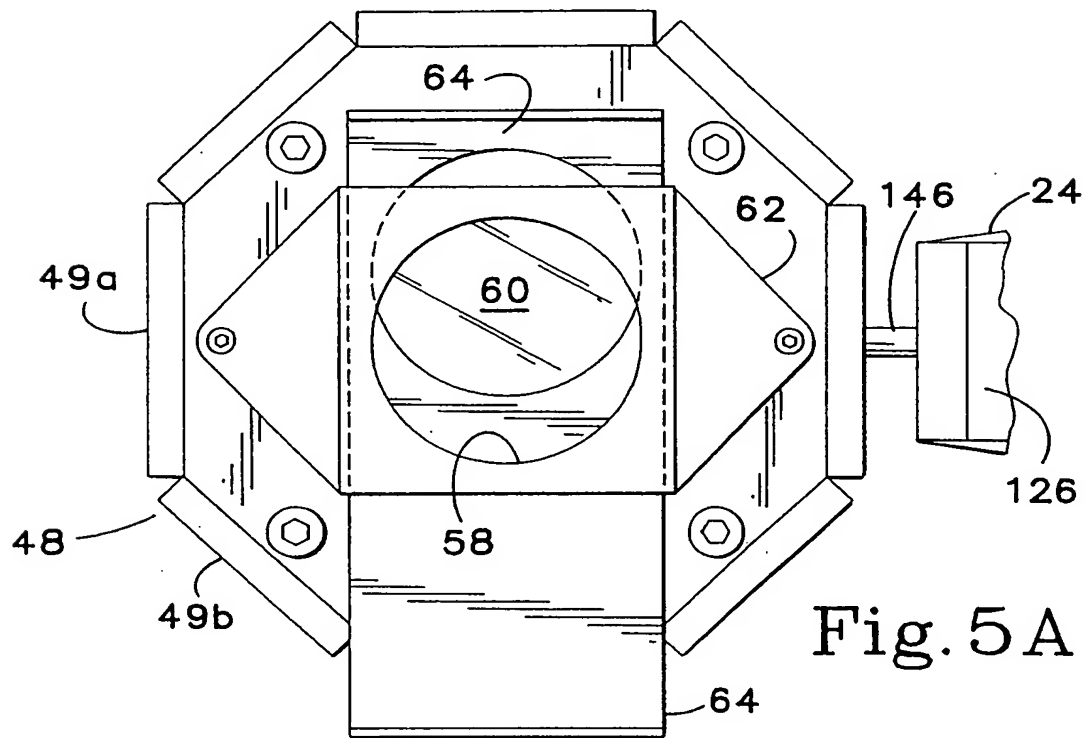
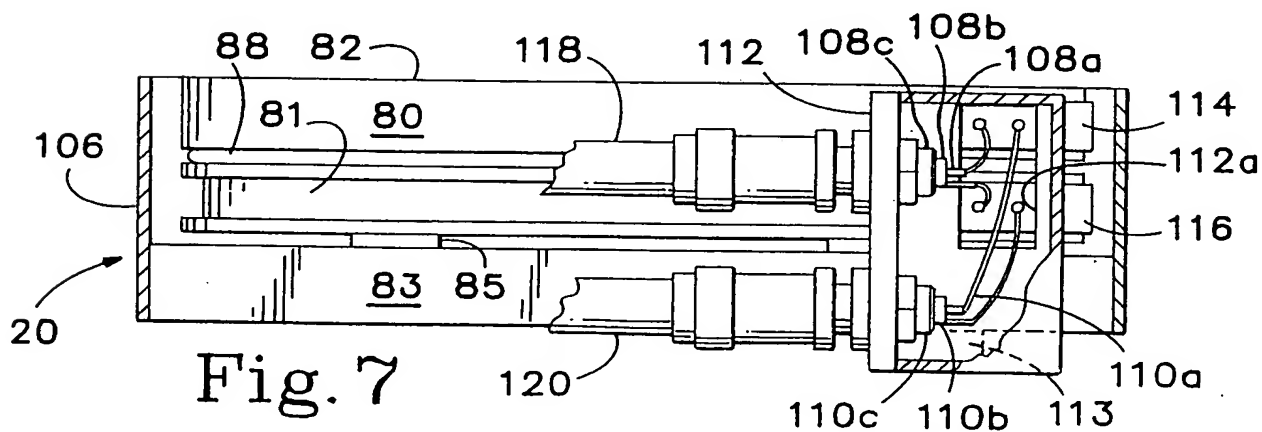
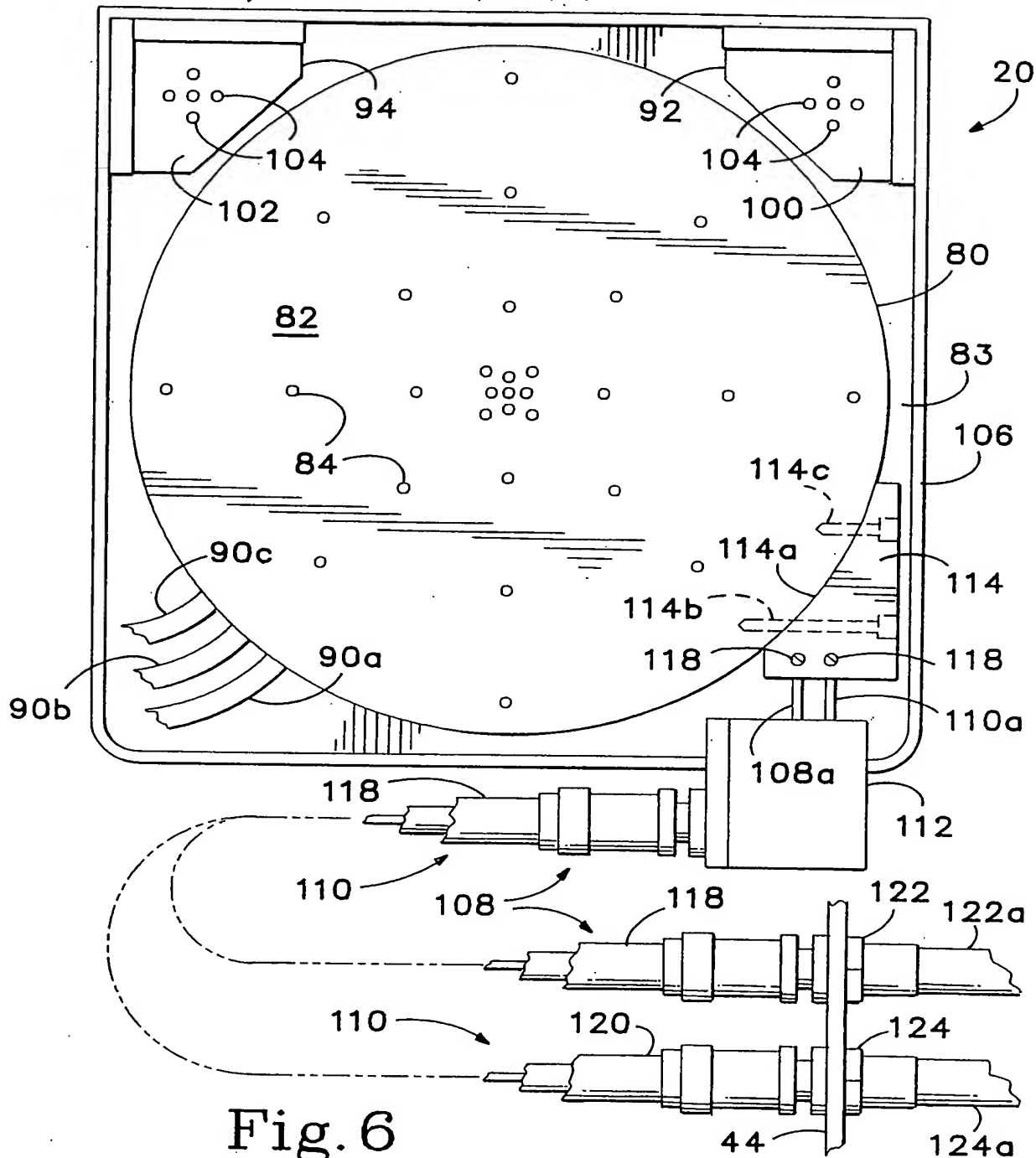
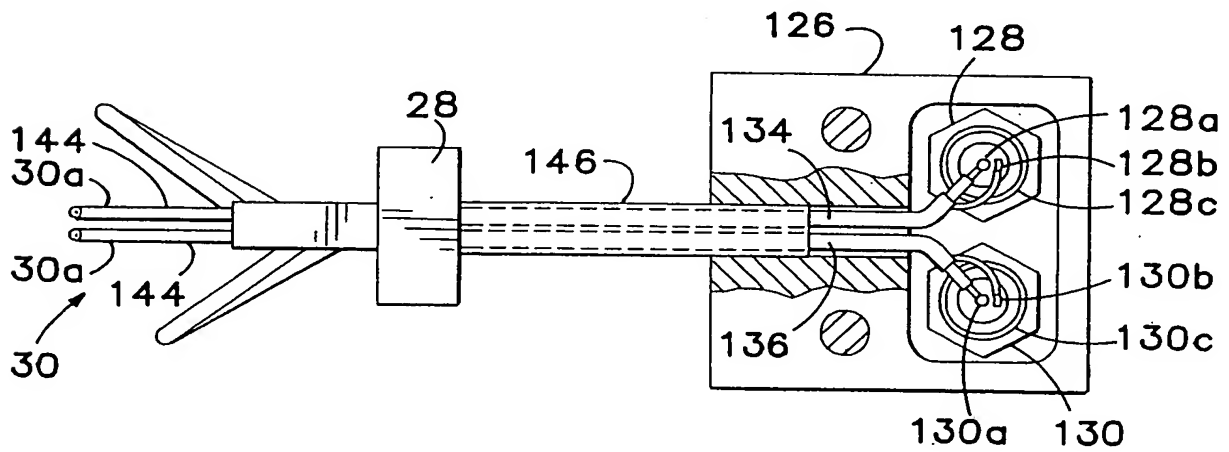
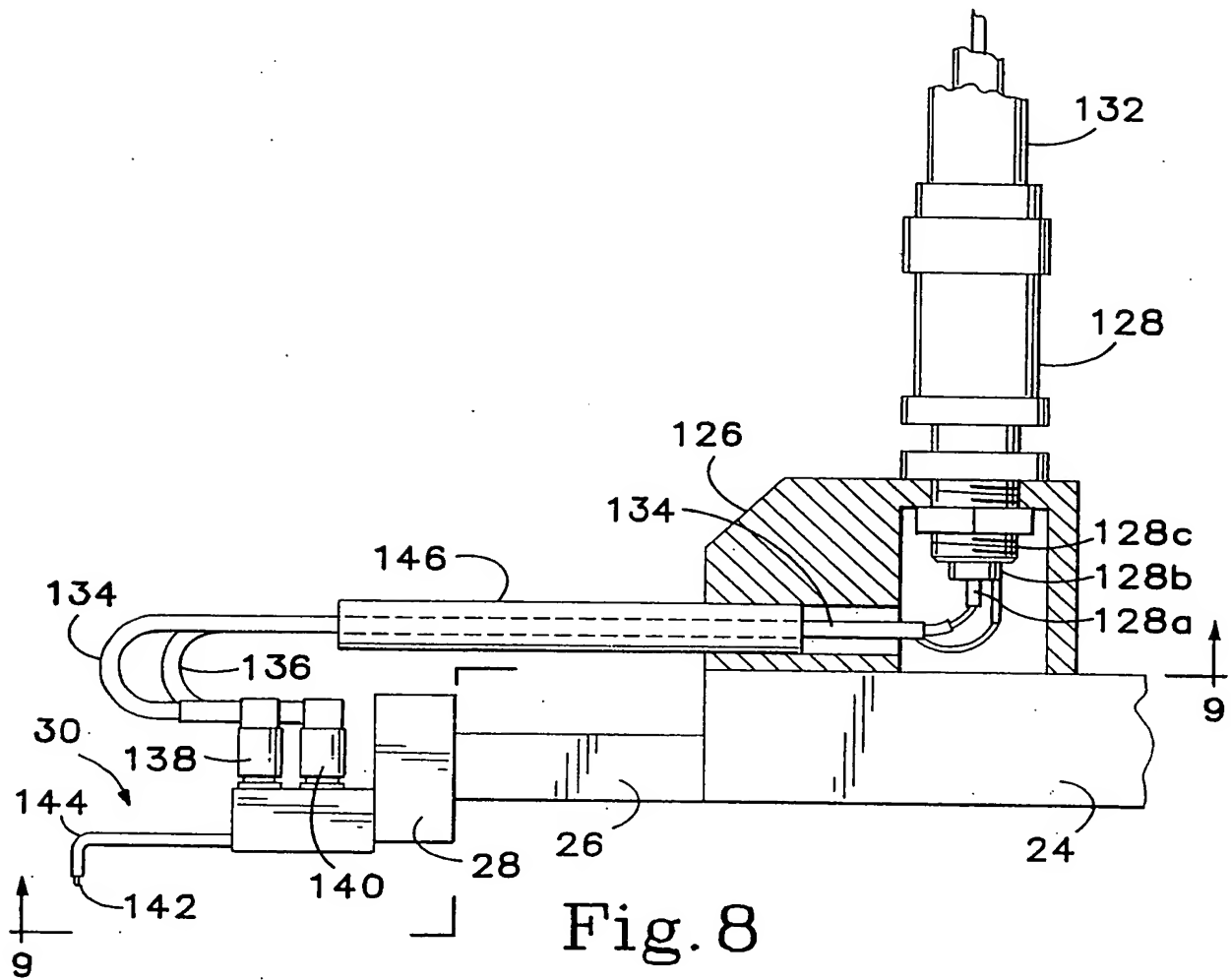
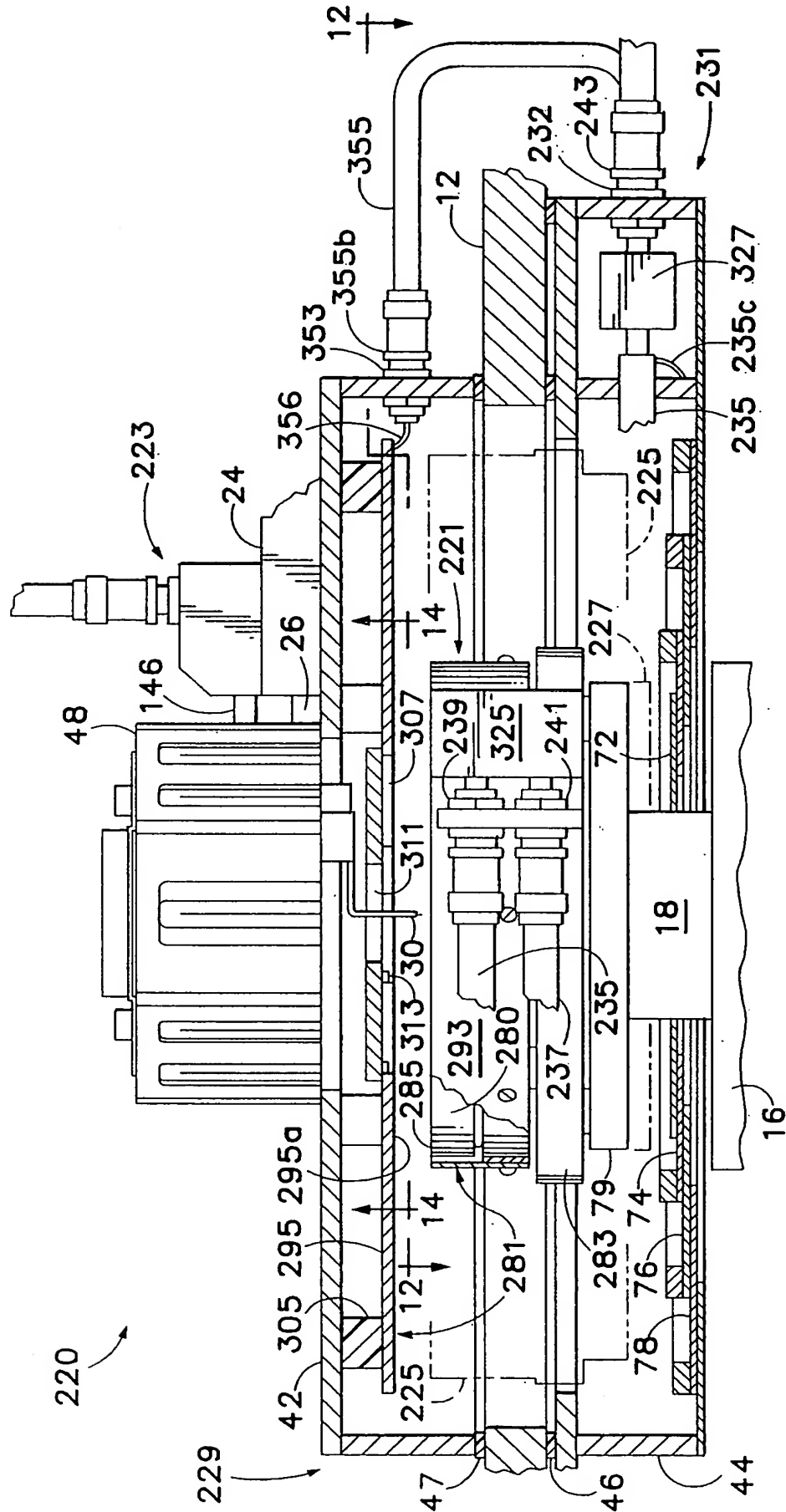


Fig. 4











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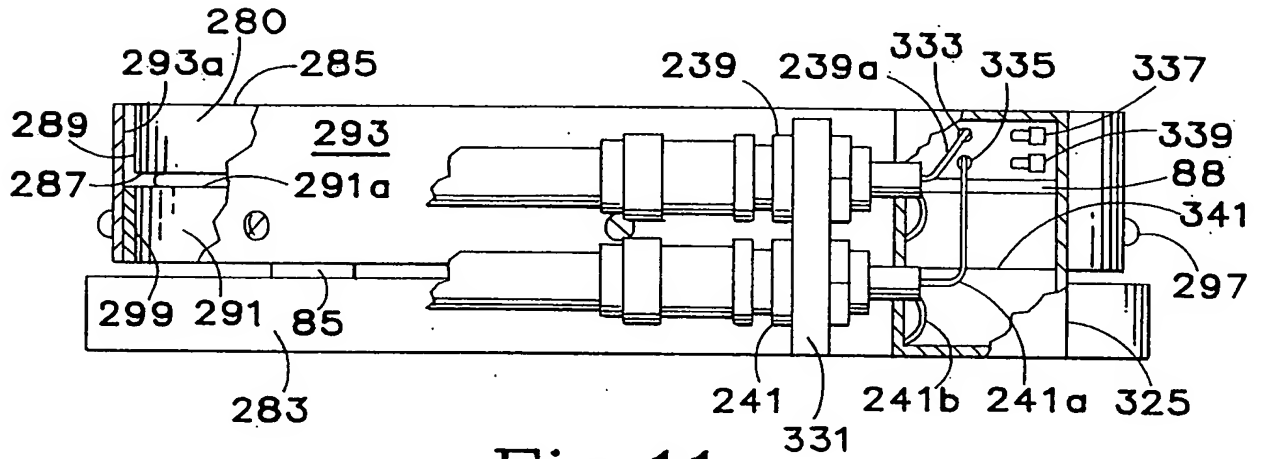


Fig. 11

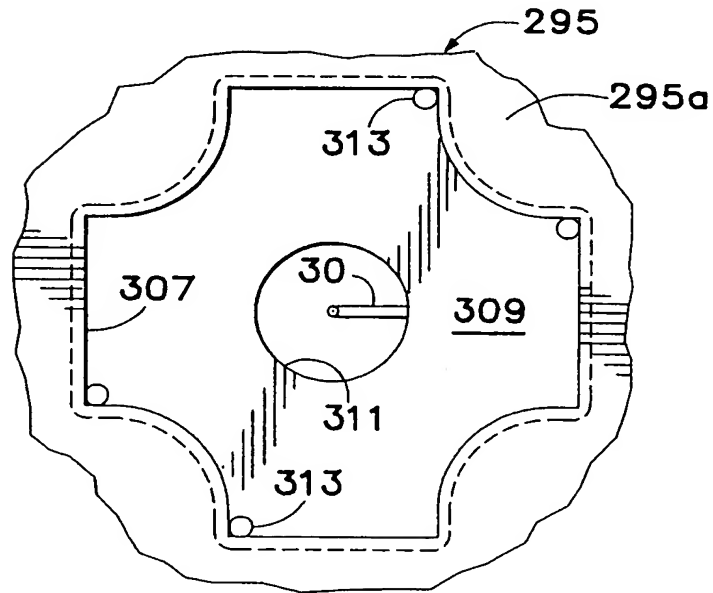


Fig. 14

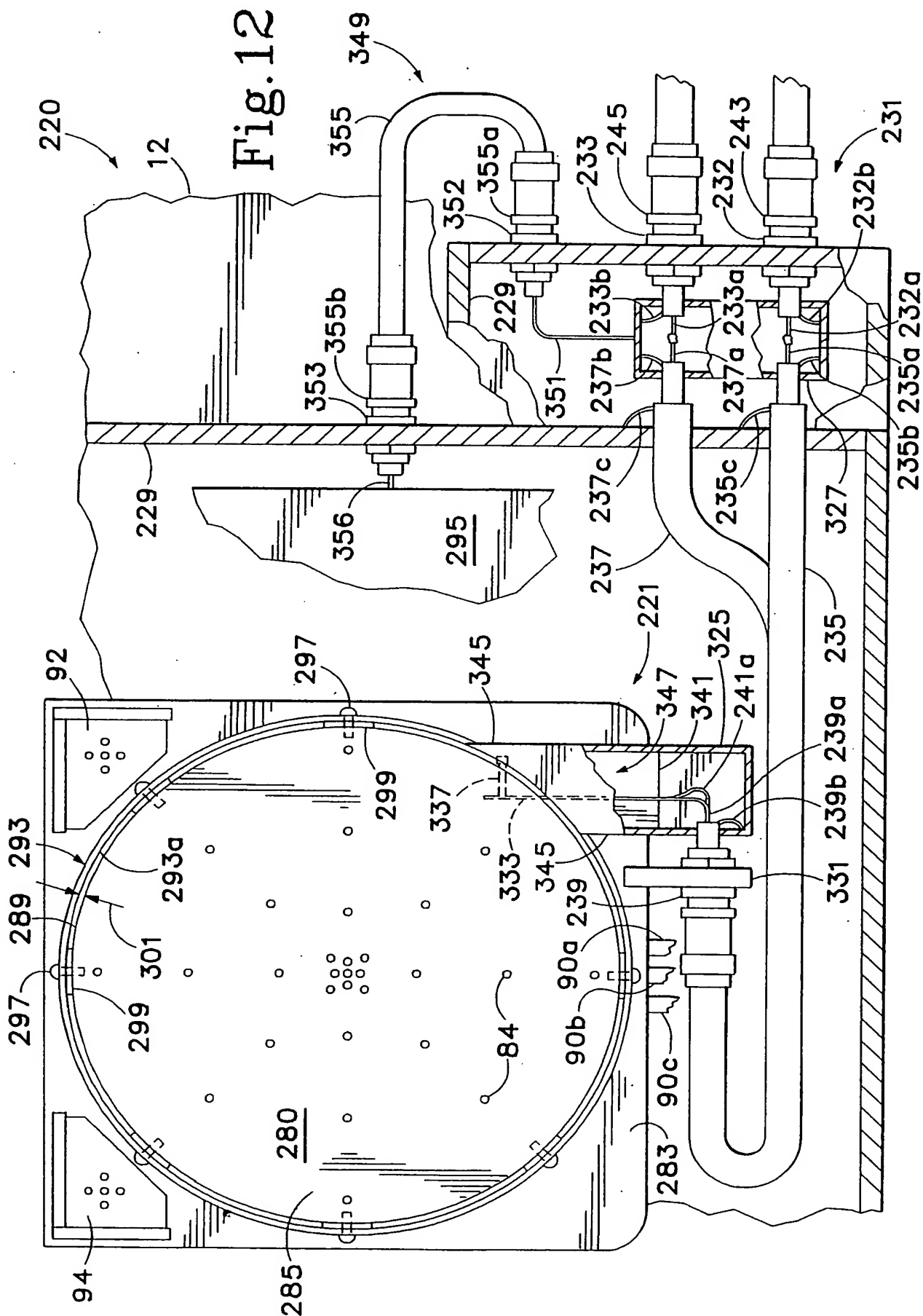


Fig. 13 is a cross-sectional view of a device 220. The device includes a curved, dome-like component 280 with a grid of small circles on its surface. A central shaft 283 passes through the center of the dome. A component 317 is located at the base of the dome, with a sub-component 317a. A dashed line 323 is shown near the base. A component 319 is located on the side of the dome. A component 325 is shown at the base of the dome. A component 315 is located on the side of the dome. A component 321 is located on the side of the dome. A component 221 is located on the side of the dome. A component 229 is located on the side of the dome. A component 70 is located at the base of the dome. A component 68 is located at the base of the dome. A component 353 is located on the side of the dome. A component 355b is located on the side of the dome. A component 355a is located on the side of the dome. A component 233 is located on the side of the dome. A component 245 is located on the side of the dome. A component 243 is located on the side of the dome. A component 232 is located on the side of the dome. A component 231 is located on the side of the dome. A component 352 is located on the side of the dome. A component 355 is located on the side of the dome.

